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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Suh, et al.

Serial No. 10/029,158

Filed: December 21, 2001

Title: APPARATUS AND METHOD FOR

CHEMICAL MECHANICAL POLISHING

OF SUBSTRATES

Examiner: Unassigned

Group Art Unit: 3723

San Francisco, CA 94111

Date: April 2, 2002

**CERTIFICATE OF MAILING** 

I hereby certify that this correspondence is being sent via U.S. Mail in an envelope addressed to the Assistant Commissioner for Patents, Washington, D.C. 20231 on

April 2, 2002

Signed:

PETITION FOR EXTENSION OF TIME

Assistant Commissioner for Patents Washington, DC 20231

Sir:

Pursuant to 37 C.F.R. 1.136(a), an extension of time of:

	Large Entity	Small Entity
One Month	/X/ \$ 110.00	//\$ 55.00
Two Months	//\$400.00	// \$ 200.00
Three Months	//\$920.00	// \$ 460.00
Four Months	/ /\$1,440.00	// \$ 720.00

is hereby requested to:

/X/ response to the Office Action mailed <u>December 21, 2001</u>; the requisite fee pursuant to 37 C.F.R. 1.17 is: /X/ enclosed by Check // to be charged to Deposit Account No. (Order No.

/X/ Please charge any additional fees or credit any overpayment to Deposit Account No. 06-1300) (Order No. <u>A-69175-1/AJT/MSS</u>).

04/17/2002 BABRAHA1 00000109 10029158

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110.00 OP

Respectfully submitted,

Maria S. Swiatek, Reg. No. 37,244

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(A-69175-1/AJT/MSS)

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